

INFORMATION DISCLOSURE CITATION PTO-1449	Atty. Docket No. 010817	Serial No. 09/891,611
Applicant: Mamoru NAKASUJI et al.		
	Filing Date: June 27, 2001	Group Art Unit:

**FOREIGN PATENT DOCUMENTS**

		Document No.	Date	Country	Translation (Yes or No)
JP 18 2002 SEARCHED SERIALIZED TRADEMAKED INDEXED JB	AC	52-115161 ✓	09/27/77	JAPAN	ABSTRACT
JB	AB	52-117567 ✓	10/03/77	JAPAN	ABSTRACT
JB	AC	57-072326 ✓	05/06/82	JAPAN	ABSTRACT
JB	AD	57-125871 ✓	08/05/82	JAPAN	ABSTRACT
JB	AE	60-000741 ✓	01/05/85	JAPAN	ABSTRACT
JB	AF	62-195838 ✓	08/28/87	JAPAN	ABSTRACT
JB	AG	03-022339 ✓	01/30/91	JAPAN	ABSTRACT
JB	AH	03-053439 ✓	03/07/91	JAPAN	ABSTRACT
JB	AI	03-102814 ✓	04/30/91	JAPAN	ABSTRACT
JB	AJ	03-266350 ✓	11/27/91	JAPAN	ABSTRACT
JB	AK	03-276548 ✓	12/06/91	JAPAN	ABSTRACT
JB	AL	04-266350 ✓	09/22/92	JAPAN	ABSTRACT
JB	AM	05-063261 ✓	03/12/93	JAPAN	ABSTRACT
JB	AN	05-251316 ✓	09/28/93	JAPAN	ABSTRACT
JB	AO	07-065766 ✓	03/10/95	JAPAN	ABSTRACT
JB	AP	08-138611 ✓	05/31/96	JAPAN	ABSTRACT
JB	AQ	09-311112 ✓	12/02/97	JAPAN	ABSTRACT
JB	AR	10-062503 ✓	03/06/98	JAPAN	ABSTRACT
JB	AS	10-177952 ✓	06/30/98	JAPAN	ABSTRACT
JB	AT	11-132975 ✓	05/21/99	JAPAN	ABSTRACT
JB	AU	2000-090868 ✓	03/31/00	JAPAN	ABSTRACT

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### U.S. PATENT DOCUMENTS

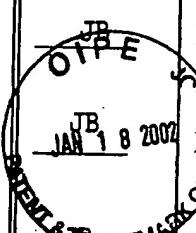
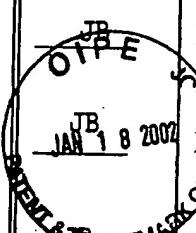
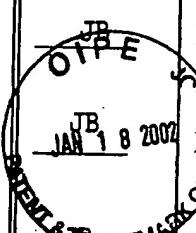
Examiner Initial	Document No.	Name	Date	Class	Subclass	Filing Date (If appropriate)
JB	6,125,522	Nakasaji	10/03/00			11/12/96
JAN 18 2002	6,087,667	Nakasaji et al.	07/11/00			09/30/97
JB	5,994,704	Nakasaji	11/30/99			10/03/97
JB	5,981,947	Nakasaji et al.	11/09/99			02/03/98
JB	5,892,224	Nakasaji	04/06/99			05/09/97
JB	5,770,863	Nakasaji	06/23/98			10/24/96
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JB	5,751,538	Nakasaji	05/12/98			09/26/96
JB	5,747,819	Nakasaji et al.	05/05/98			10/30/96
JB	5,362,968	Miyoshi et al.	11/08/94			09/27/93
JB	5,359,197	Komatsu et al.	10/25/94			07/16/93
JB	4,912,052	Miyoshi et al.	03/27/90			09/23/88

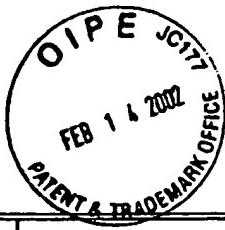
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JB	BH ✓	Low Voltage and high speed operating electrostatic wafer chuck using sputtered tantalum oxide membrane, Mamoru Nakasaji et al., J. Vac. Sci. Technol. A 12(5), Sep/Oct 1994, American Vacuum Society pp. 2834-2839.
JB	BI ✓	High -Emittance and Low-Brightness Electron Gun for Reducing-Image Projection System: Computer Simulation, Mamoru Nakasaji et al., Jpn. J. Appl. Phys. Vol. 36 (1997) pp.2404-2408.
JB	BJ ✓	H. Hayashi, et al., LSI Testing Symposium 1998, Minutes of the meeting, P160 (1998) (partial translation)

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**OTHER DOCUMENTS**

<b>INFORMATION DISCLOSURE CITATION PTO-1449</b>	Atty. Docket No. <b>010817</b> Serial No. <b>09/891,611</b>	Applicant: <b>Mamoru NAKASUJI et al.</b> Filing Date: <b>June 27, 2001</b> Group Art Unit:												
<table border="1" style="width: 100%; border-collapse: collapse;"> <tr> <td style="width: 15%; vertical-align: top; padding: 5px;">  </td> <td style="width: 15%; vertical-align: top; padding: 5px;"> <b>BK</b> ✓       </td> <td style="width: 70%; vertical-align: top; padding: 5px;"> <i>Multi-Beam Concepts for Nanometer Devices</i>, B. Lischke et al., Japanese Journal of Applied Physics, Vol. 28, No.10, October 1989, pp. 2058-2064.       </td> </tr> <tr> <td style="vertical-align: top; padding: 5px;"> <b>BL</b> </td> <td style="vertical-align: top; padding: 5px;"> </td> <td style="vertical-align: top; padding: 5px;"> <i>An electron-beam inspecting system for x-ray mask production</i>, P. Sandland et al., J. Vac. Sci. Technol. B9 (6), Nov/Dec. 1991, American Vacuum Society, pp.3005-3009.       </td> </tr> <tr> <td style="vertical-align: top; padding: 5px;"> <b>BM</b> </td> <td style="vertical-align: top; padding: 5px;"> </td> <td style="vertical-align: top; padding: 5px;"> <i>Requirements and performance of an electron-beam column designed for x-ray mask inspection</i>, W.D. Meisburger et al., J. Vac. Sci. Technol. B9 (6), Nov/Dec 1991, American Vacuum Society, pp.3010-3014.       </td> </tr> <tr> <td style="vertical-align: top; padding: 5px;"> <b>JB</b> </td> <td style="vertical-align: top; padding: 5px;"> <b>BN</b> </td> <td style="vertical-align: top; padding: 5px;"> <i>Table 5-1 Work Function in Metals</i> page 116.       </td> </tr> </table>				<b>BK</b> ✓	<i>Multi-Beam Concepts for Nanometer Devices</i> , B. Lischke et al., Japanese Journal of Applied Physics, Vol. 28, No.10, October 1989, pp. 2058-2064.	<b>BL</b>		<i>An electron-beam inspecting system for x-ray mask production</i> , P. Sandland et al., J. Vac. Sci. Technol. B9 (6), Nov/Dec. 1991, American Vacuum Society, pp.3005-3009.	<b>BM</b>		<i>Requirements and performance of an electron-beam column designed for x-ray mask inspection</i> , W.D. Meisburger et al., J. Vac. Sci. Technol. B9 (6), Nov/Dec 1991, American Vacuum Society, pp.3010-3014.	<b>JB</b>	<b>BN</b>	<i>Table 5-1 Work Function in Metals</i> page 116.
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#### U.S. PATENT DOCUMENTS

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JB	AA	4,944,645	Suzuki	7/31/90			
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JB	AD	2000-67798 ✓	3/3/00	Japan	Yes/Abstract
JB	AE	09-073872 ✓	3/18/97	Japan	Yes/Abstract
JB	AF	2000-100369 ✓	4/7/00	Japan	Yes/Abstract
JB	AG	2000-003692 ✓	1/7/00	Japan	Yes/Abstract
JB	AH	2000-133565 ✓	5/12/00	Japan	Yes/Abstract
JB	AI	62-100936 ✓	5/11/87	Japan	Yes/Abstract
JB	AJ	10-125271 ✓	5/15/98	Japan	Yes/Abstract
JB	AK	11-233062 ✓	8/27/99	Japan	Yes/Abstract
JB	AL	2000-149843 ✓	5/30/00	Japan	Yes/Abstract
	AM				

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	AN	
	AO	

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